

Edge-on technique using a high energy electron beam for characterization of irradiated pad diodes

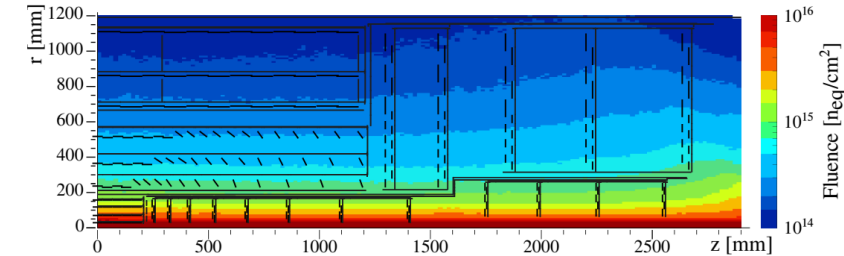
M. Hajheidari, E. Garutti, J. Schwandt, A. Ebrahimi

Institute for Experimental Physics, University of Hamburg

16th Trento workshop

Introduction

- Luminosity in the CMS Phase-2 is up to $7.5 \times 10^{34} \text{ cm}^{-2} \text{ s}^{-1}$.
- This causes a neutron equivalent fluence of $2.3 \times 10^{16} \text{ cm}^{-2}$ (after 3000 fb^{-1}) in the first layer.
- The radiation damage changes the electric field and trapping times of the sensors used in the inner tracker.



The motivation of this talk

- Understanding the charge collection in highly irradiated silicon diodes

The tool of study

- Edge-on measurement using electron beam with an energy of 4.0 GeV

The performed measurements

- Charge profiles of non-irradiated and irradiated diodes at different bias voltages

After 3000 fb^{-1}

Layer	$\Phi_{\text{eq}} [10^{16} \text{ cm}^{-2}]$
1	2.3
2	0.5
3	0.2
4	0.15

Introduction

Issues of top TCT measurements with short absorption length radiation:

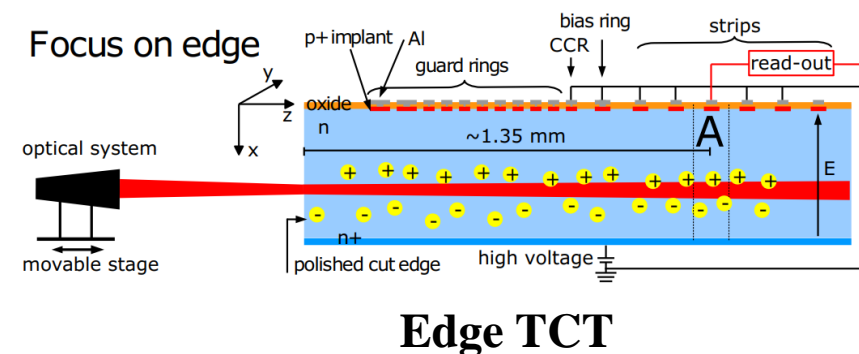
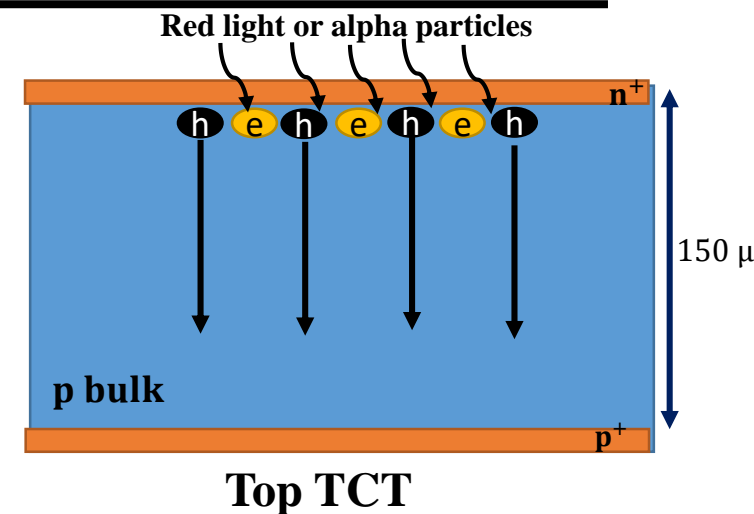
- Difficult to obtain information about charge collection as a function of depth in the sensor
- Very sensitive to any inactive layers at sensor implants

Issues of edge TCT measurement with laser light:

- Changing of the beam radius as it travels into the sensor
- Sensitive to quality of the polished edge
- Commonly used for segmented sensors (complicated weighting filed)
- **The measurements cannot be normalized to an absolute value**

Proposal:

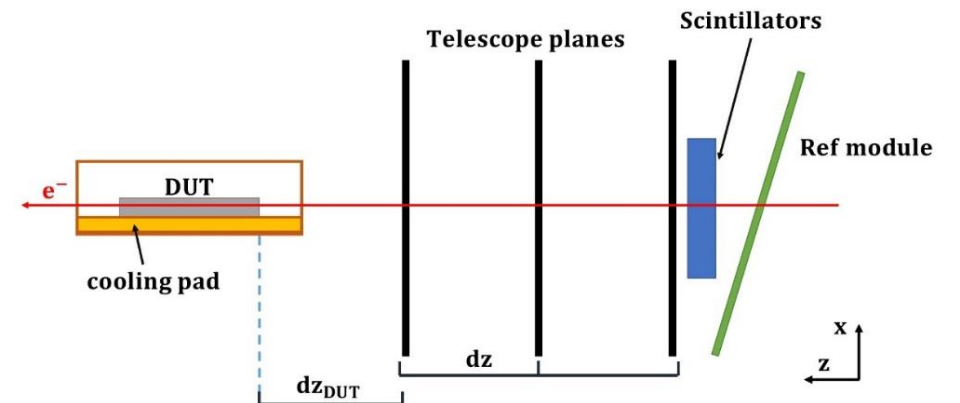
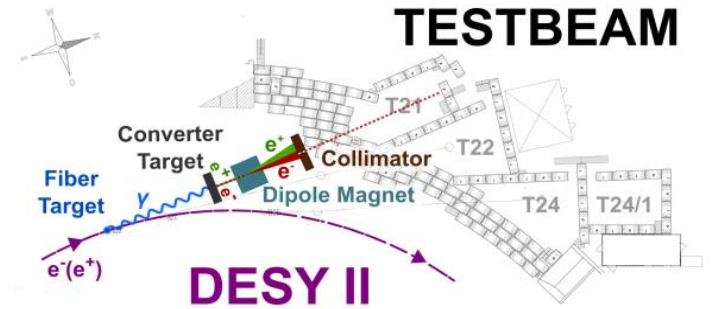
- Using electron beam for characterizing pad diodes with edge-on measurements



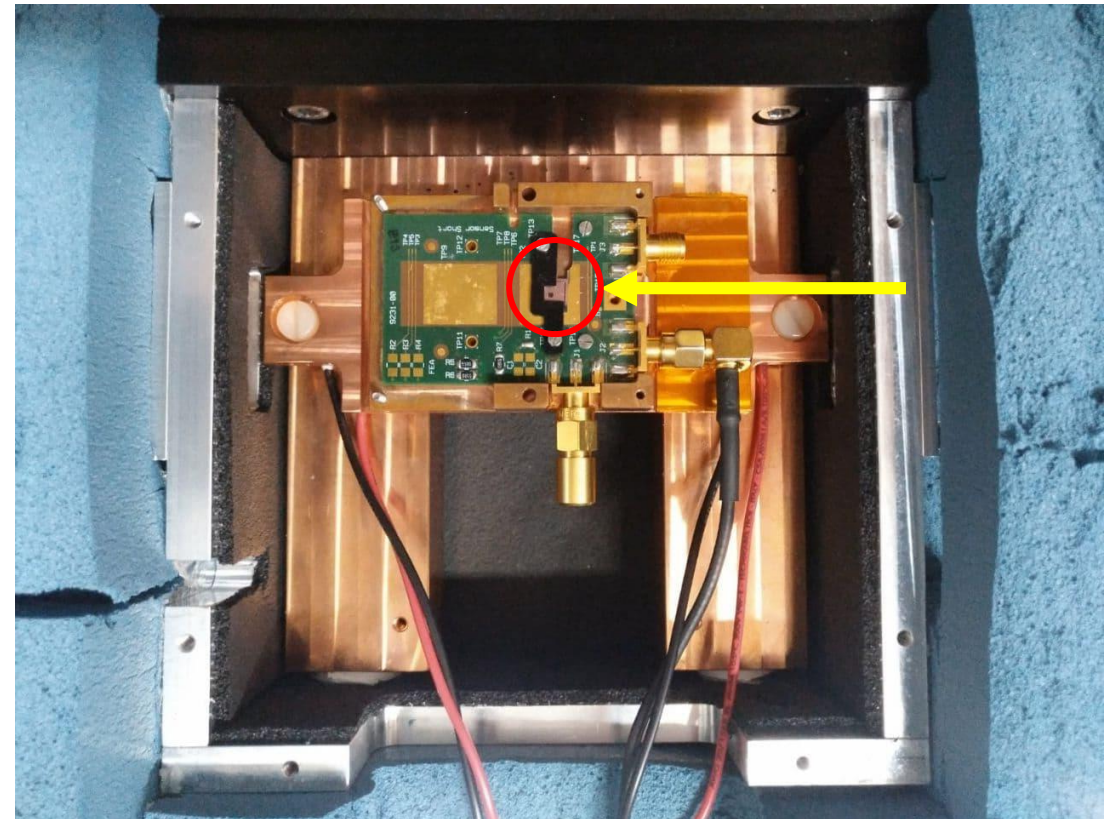
Measurement setup

DESY II beam test facility:

- Electron/positron beam with energy of 1-6 GeV
- Beam energy of 4.0 GeV was chosen for the measurements
- Three telescope planes for the track reconstruction
- Intrinsic resolution of telescope $\approx 5 \mu\text{m}$
- Timing reference module for reducing in-time pile up
- Scintillator for providing the readout trigger ($8 \times 3 \text{ mm}^2$ triggering area)
- Rotation stage for the DUT with a precision of 0.25° (4 mrad)



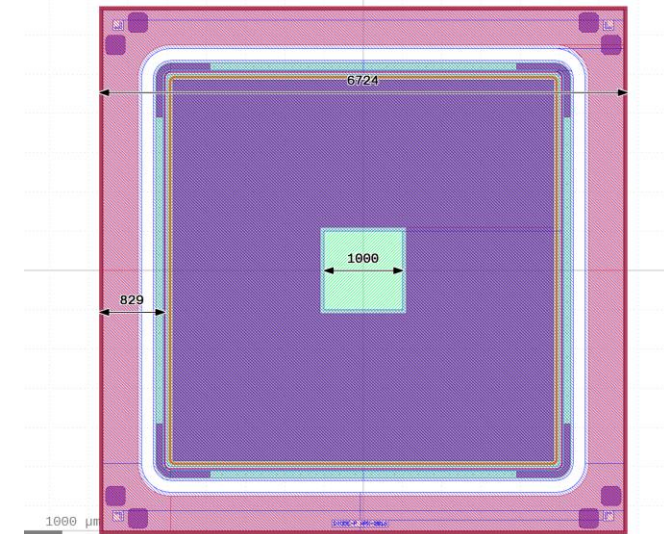
Measurement setup



Specifications of the studied diodes

- Active thickness 150 μm
- Area $\approx 25 \text{ mm}^2$
- p-type (n^+pp^+ configuration)
- Doping concentration $\approx 4.5 \times 10^{12} \text{ cm}^{-3}$
- Depletion voltage 75 V
- Manufactured by Hamamatsu Photonic K.K (HPK)
- Guard-ring is floating

Top view (dimensions are in micrometer)



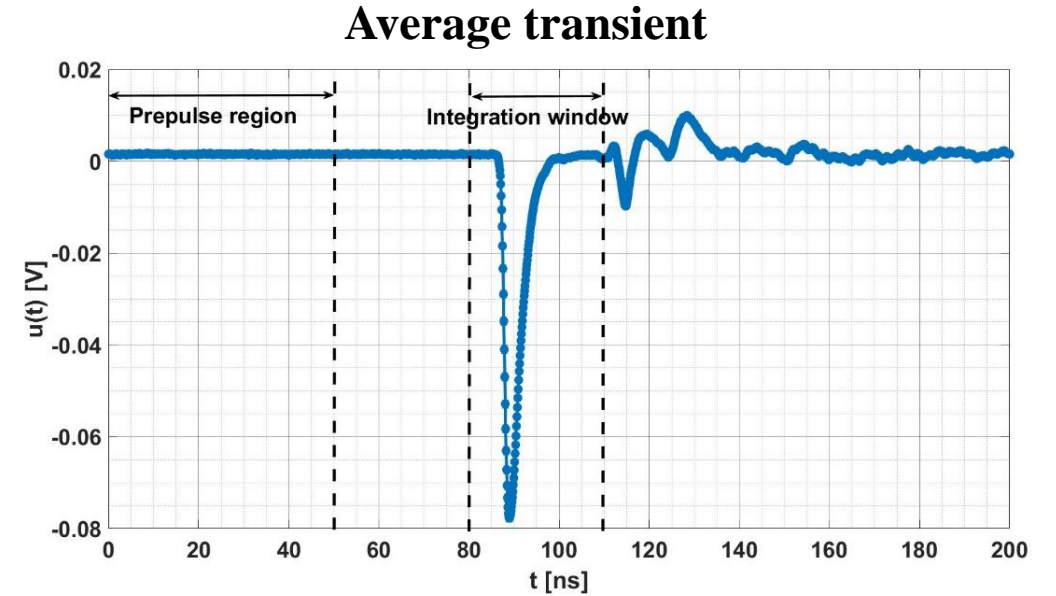
For irradiation study

- Irradiation with 23 MeV protons at Karlsruhe Institute of Technology (KIT)
- Irradiation to equivalent fluence $\Phi_{\text{eq}} = 2 \text{ and } 4 \times 10^{15} \text{ cm}^{-2}$ (hardness factor of $\kappa = 2.2$)

Collected charge measurement

- Transients of the diode ($u_0(t)$) are recorded
- The average of transients in the prepulse region is subtracted from the whole (baseline correction)
- Collected charge for the diode is given as

$$Q_0 = \int_{t_0}^{t_1} \frac{u_0(t)}{G \cdot R_L} dt, \quad R_L = 50 \Omega, G = 100, t_1 - t_0 = 30 \text{ ns}$$



In-situ alignment procedure

Purpose of in-situ alignment:

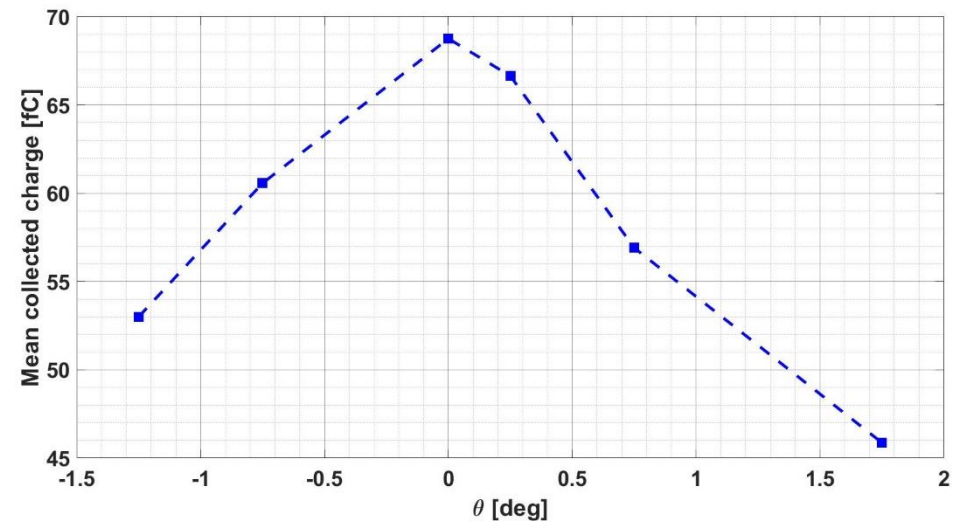
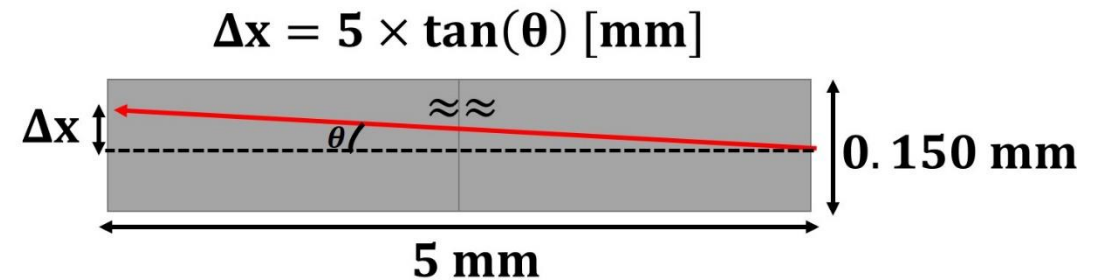
- Find the angle in which tracks are parallel with the diode surface, i.e. $\theta = 0$

Procedure of in-situ alignment:

- Rotation of the DUT with small steps (0.25°)
- Calculate the mean collected charge of the diode
- Find the angle in which collected charge is maximum

Advantage of using this procedure:

- No track reconstruction is required
- Independent of the telescope resolution



On-line alignment procedure

Measurement conditions:

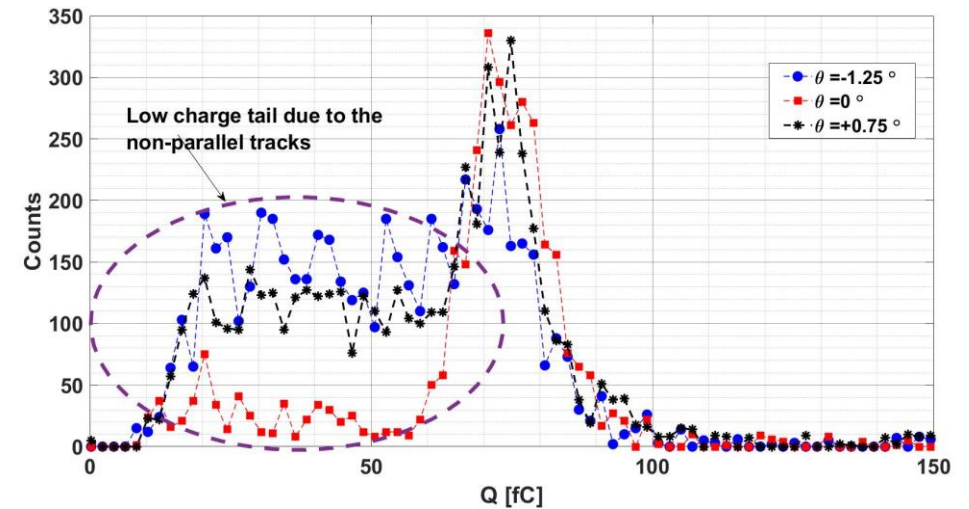
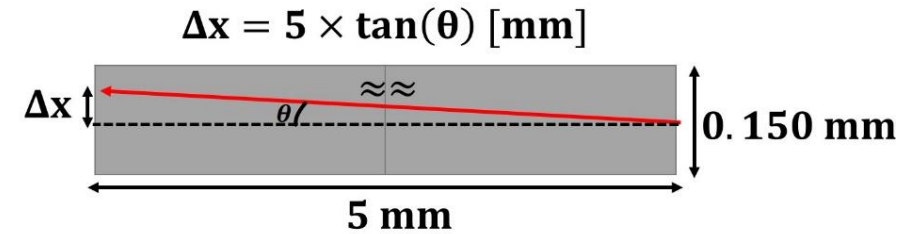
- Room temperature
- $V_{\text{bias}} = 100 \text{ V}$
- $\theta: -1.25^\circ, 0^\circ, +0.75^\circ$

DUT:

- Non-irradiated

Observations:

- At non-zero θ , tracks close to the surface leave the diode, therefore charge distribution has a low charge tail.
- By rotating the DUT with fine steps, the best angle of incident could be achieved.
- This procedure has to be repeated for each diode.



Charge profile, non-irradiated diode

Measurement conditions:

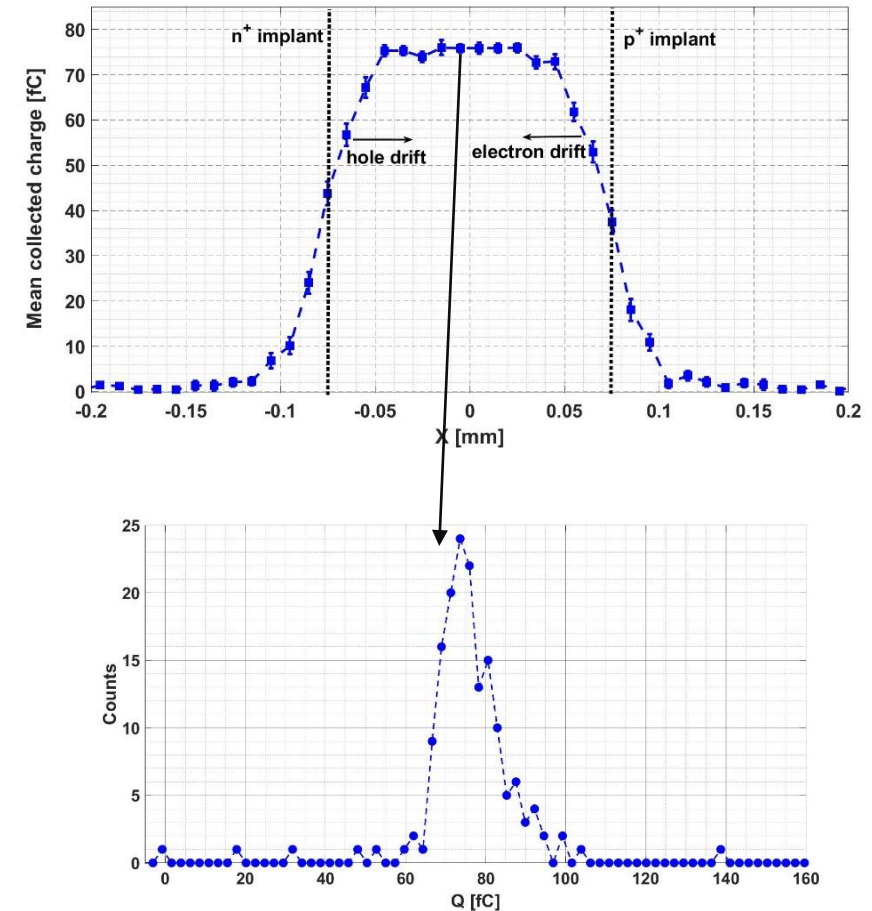
- Room temperature
- $V_{\text{bias}} = 100 \text{ V}$
- $\theta : 0^\circ$
- Beam divergence: $\pm 1 \text{ mrad}$

DUT:

- Non-irradiated diode

Observations:

- Charge distribution is uniform as a function of beam position with $10 \mu\text{m}$ bin width.



Charge profile, non-irradiated diode

Estimation of the diode thickness:

- Fit an error function to the rising edge of profile:

$$F_1(x) = A_1 \left(0.5 + 0.5 \cdot \operatorname{erf} \left(\frac{x - \mu_1}{\sqrt{2}\sigma_1} \right) \right)$$

- Fit an error function to the falling edge of profile:

$$F_2(x) = A_2 \left(0.5 - 0.5 \cdot \operatorname{erf} \left(\frac{x - \mu_2}{\sqrt{2}\sigma_2} \right) \right)$$

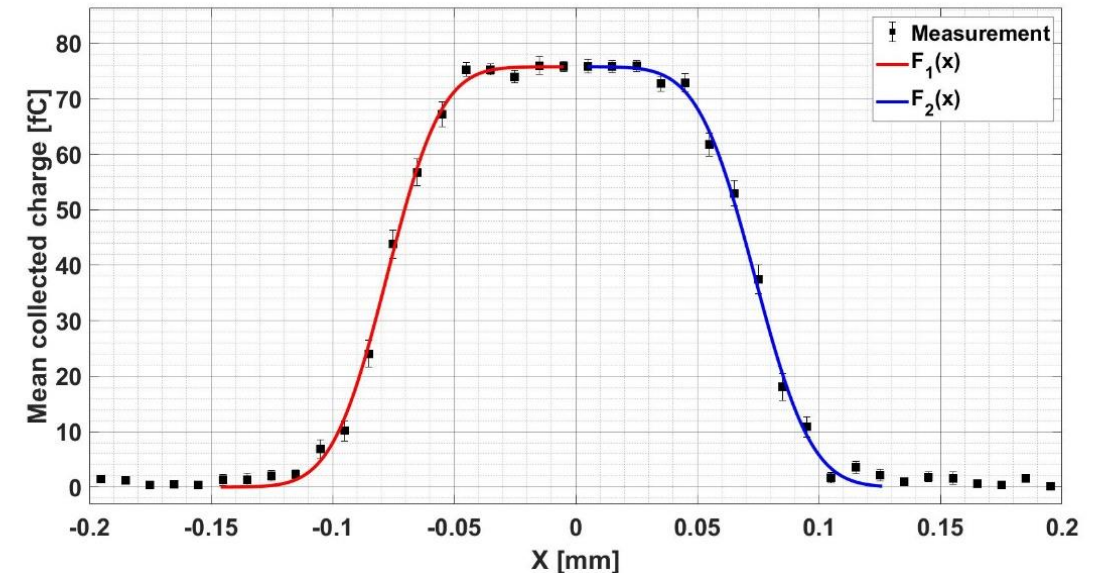
- Thickness of the diode is estimated as:

$$t_{\text{diode}} = \mu_2 - \mu_1$$

The result of the estimation:

$$t_{\text{diode}} = 151.4 \pm 1.15 \mu\text{m}$$

$$\sigma_1 \approx \sigma_2 \approx 18 \mu\text{m}$$



Charge profile, irradiated diode

Measurement conditions:

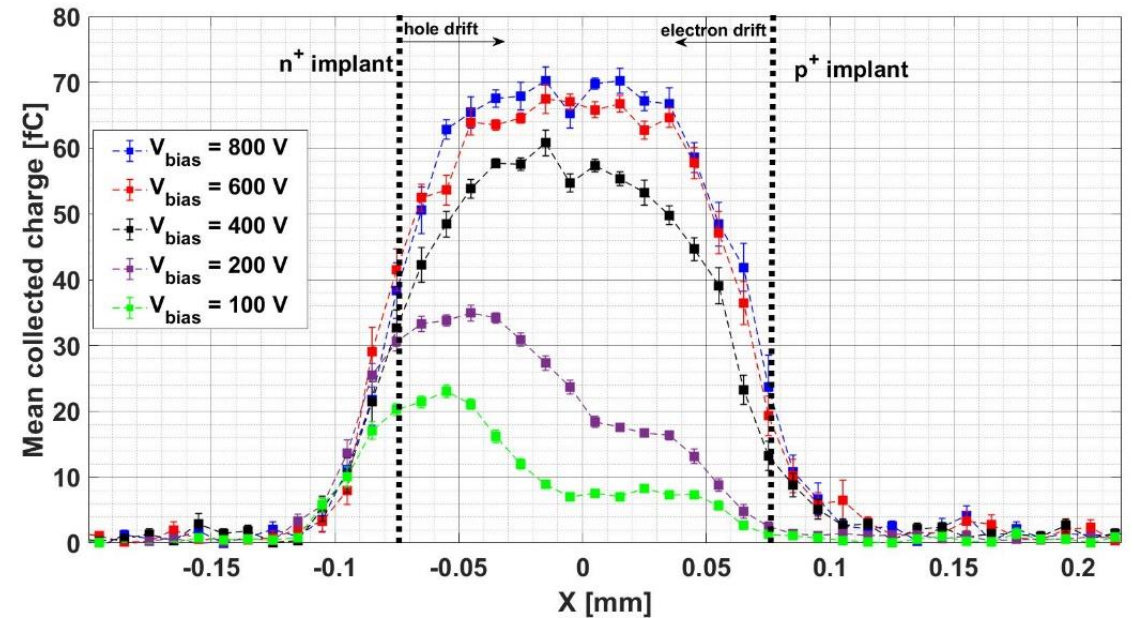
- Temperature: -20 C
- $V_{\text{bias}} = 800, 600, 400, 200, 100$ V
- Angle of incident: 0°

DUT:

- Proton irradiated at $\Phi_{\text{eq}} = 2 \times 10^{15} \text{ cm}^{-2}$

Observations:

- Charge profile is not uniform as a function of beam position.
- Holes have a higher charge collection than electrons



Charge profile, irradiated diode

Measurement conditions:

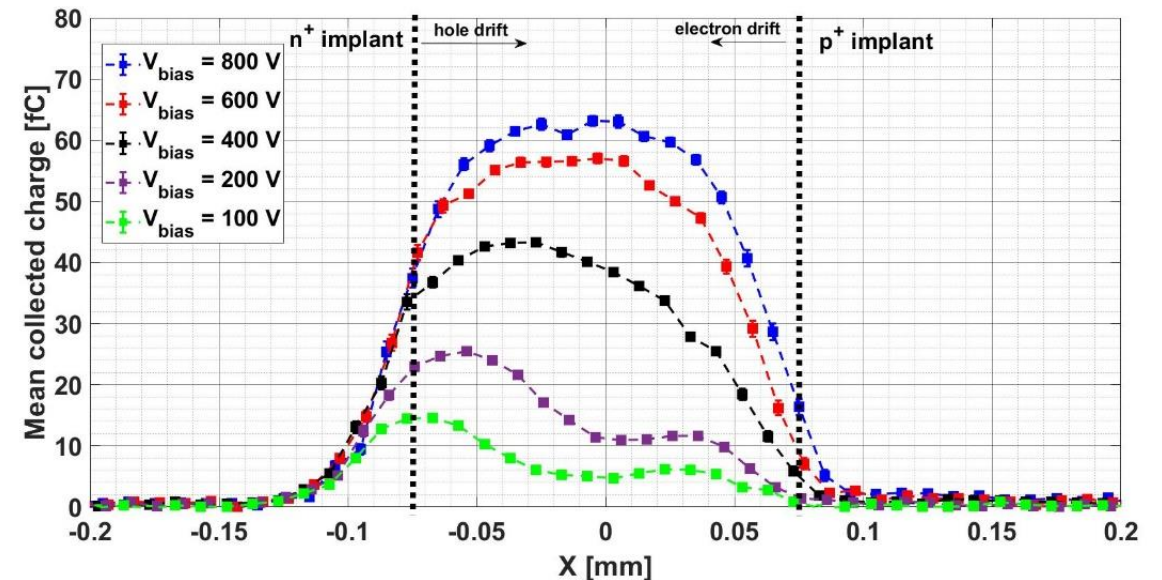
- Temperature: -20 C
- $V_{\text{bias}} = 800, 600, 400, 200, 100$ V
- Angle of incident: 0°

DUT:

- Proton irradiated at $\Phi_{\text{eq}} = 4 \times 10^{15} \text{ cm}^{-2}$

Observations:

- Charge profile is not uniform as a function of beam position.
- Holes have a higher charge collection than electrons



CCE as a function of bias voltage

Measurement conditions:

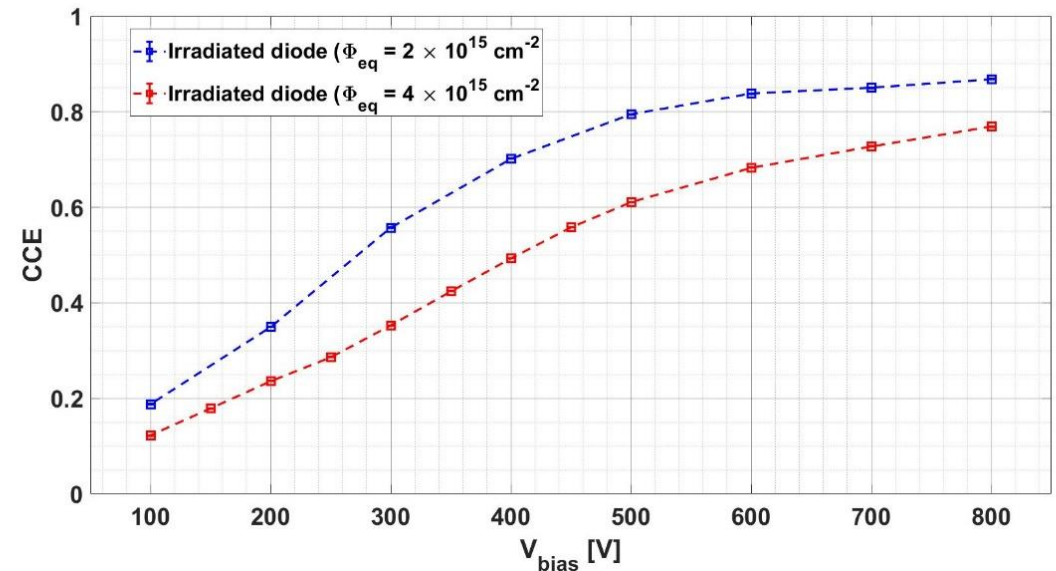
- Temperature: -20 C
- $V_{\text{bias}} = 100 - 800$ V
- Angle of incident: 0°

DUT:

- Proton irradiated at $\Phi_{\text{eq}} = 2$ and $4 \times 10^{15} \text{ cm}^{-2}$

CCE is calculated as:

$$\text{CCE}(V_{\text{bias}}) = \frac{\sum_{x=-150 \mu\text{m}}^{+150 \mu\text{m}} Q_{x,\text{irradiated}}(V_{\text{bias}})}{\sum_{x=-150 \mu\text{m}}^{+150 \mu\text{m}} Q_{x,\text{non-irradiated}}}$$



Summary and outlook

Summary

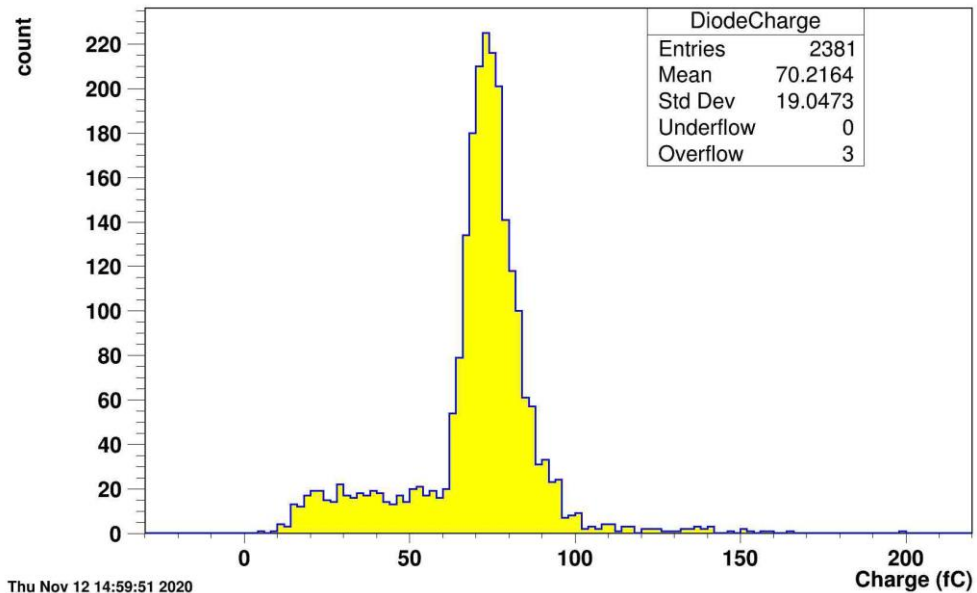
- Edge-on measurement can be used to obtain charge collection as a function of depth in irradiated pad diodes.
- In this work, the method was implemented using the high energy electron beam.
- The advantages of using the electron beam are:
 - It can be used for pad diodes
 - The charge profiles can be normalized to an absolute value
- This work introduces a procedure for in-situ alignment of the beam direction with respect to the DUT surface.
- Charge profiles were obtained for one non-irradiated and two irradiated diodes
- By using the charge profiles, CCE of irradiated diodes were estimated

Outlook

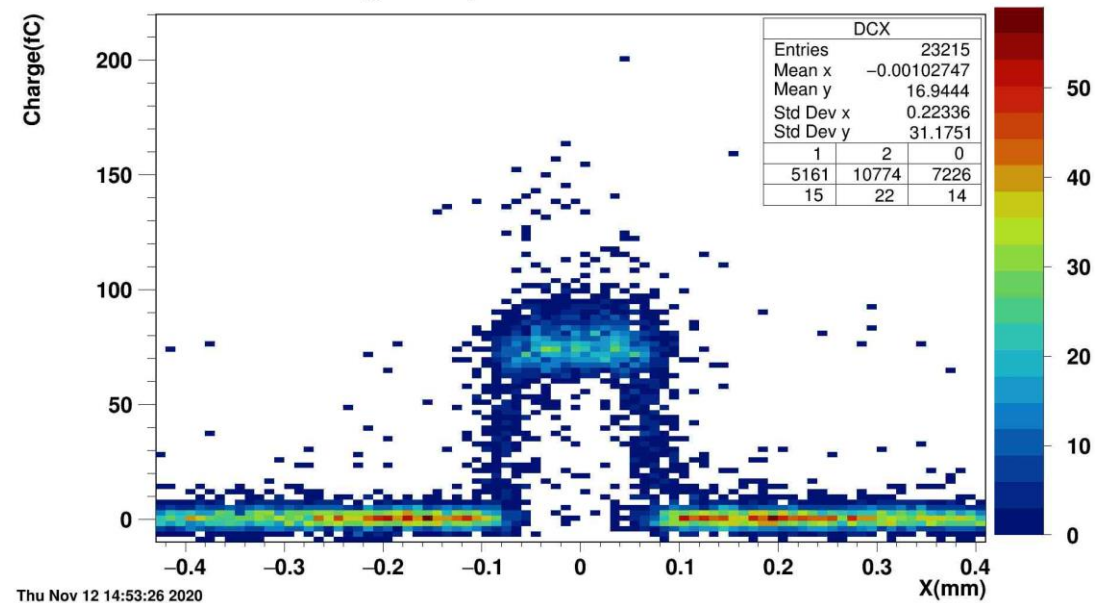
- Compare the measured charge profiles with results of the simulations (from TCAD model)
- Trying to calibrate the results of pixel measurements using the edge-on diode results
- Repeat the method for higher irradiation fluence

Back up, charge profile and charge distribution

Charge of events with Index_Over_Thr



Charge 2-D profile in X direction



Charge distributions , irradiated and non-irradiated diodes

Measurement conditions:

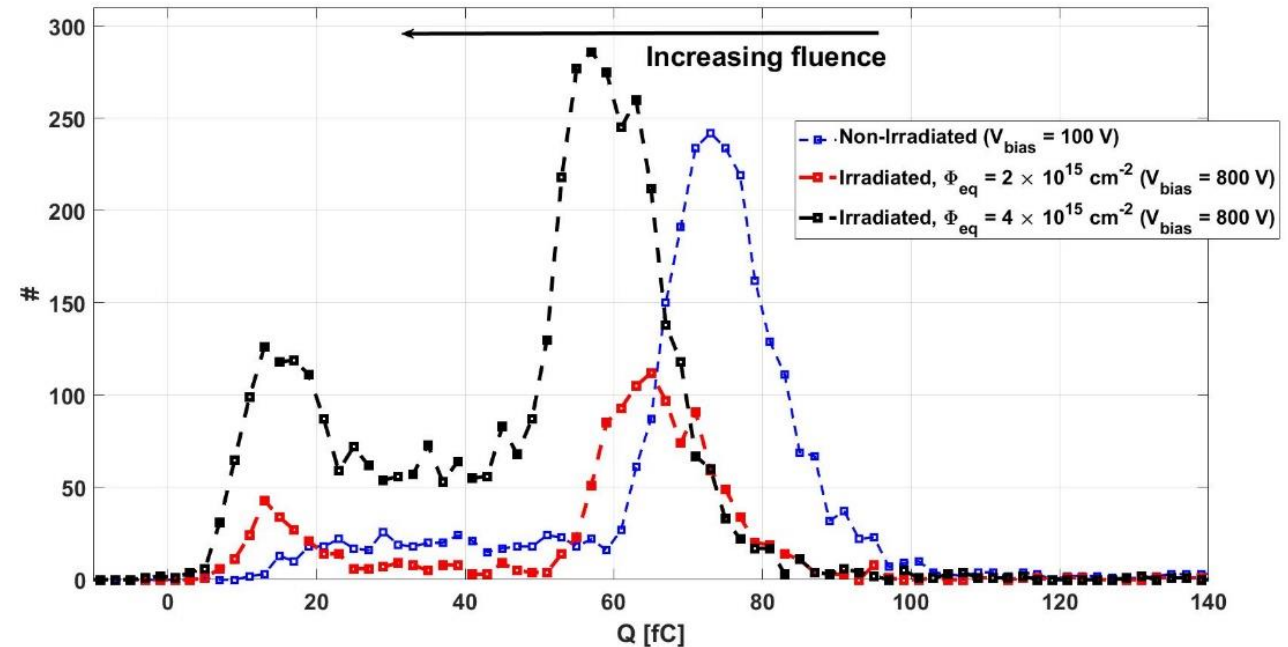
- Temperature: -20 C
- $V_{\text{bias}} = 800, 100 \text{ V}$
- Angle of incident: 0°

DUTs:

- Proton irradiated at $\Phi_{\text{eq}} = 0, 2$ and $4 \times 10^{15} \text{ cm}^{-2}$

Observations:

- The total charge distribution is shifted to the lower charge as the irradiation fluence increases.



Charge distributions , irradiated and non-irradiated diodes

Measurement conditions:

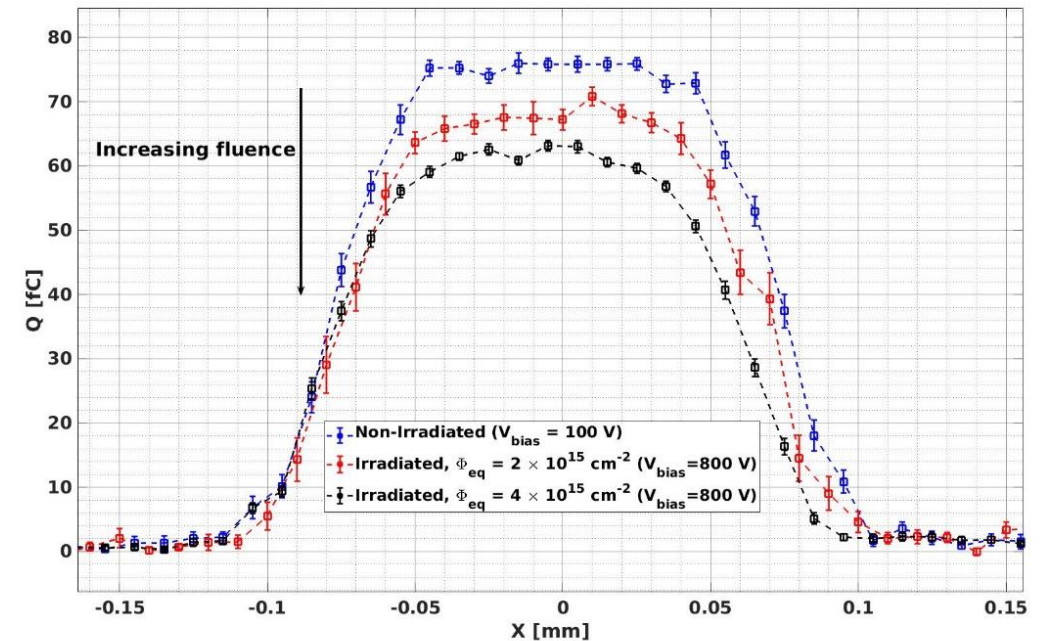
- Temperature: -20 C
- $V_{\text{bias}} = 800, 100 \text{ V}$
- Angle of incident: 0°

DUTs:

- Proton irradiated at $\Phi_{\text{eq}} = 0, 2 \text{ and } 4 \times 10^{15} \text{ cm}^{-2}$

Observations:

- The total charge distribution is shifted to the lower charge as the irradiation fluence increases.

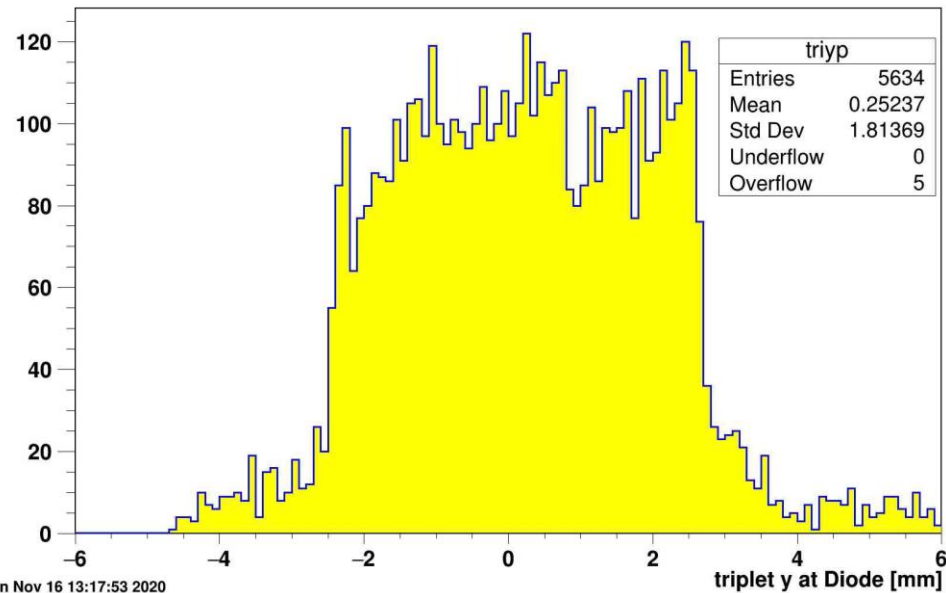


Back up, Geometrical cuts

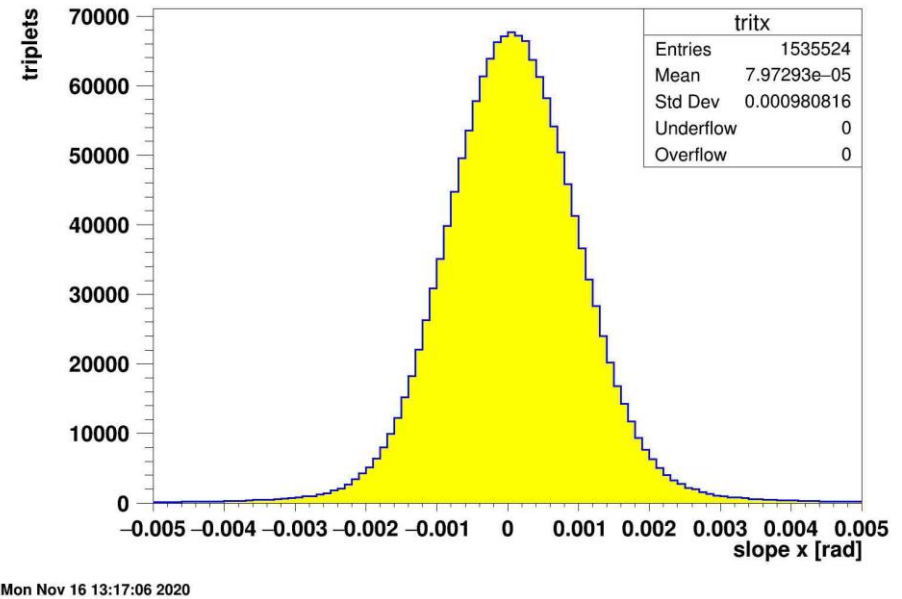
$$|y_{\text{dut}}| < 2.5 \text{ mm}$$

$$|\theta_x| < 1 \text{ mrad}$$

triplet y with pulse



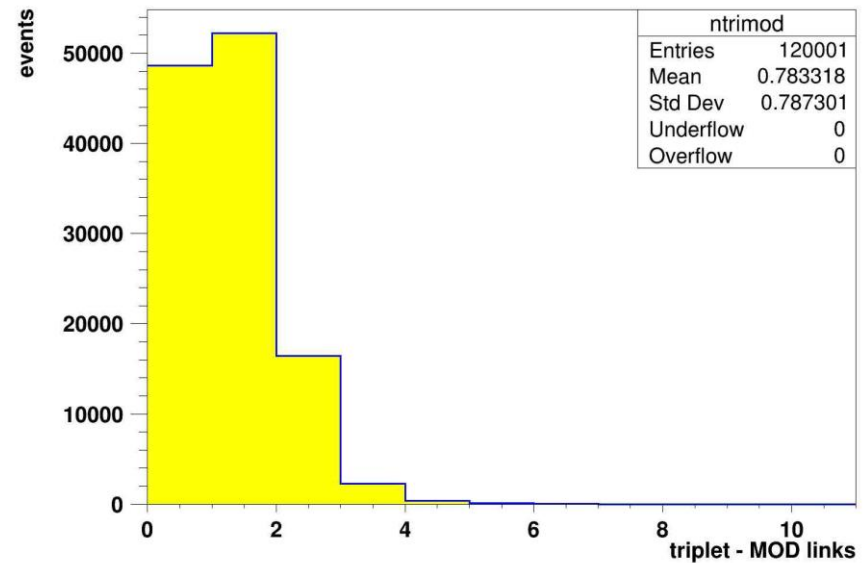
triplet slope x



Back up, Cuts on number of tracks per event

$$|N_{\text{tracks}}| < 2$$

triplet - MOD links



Mon Nov 16 16:20:24 2020

Hit map of the DUT

Measurement conditions:

- Room temperature
- $V_{\text{bias}} = 100 \text{ V}$

DUT:

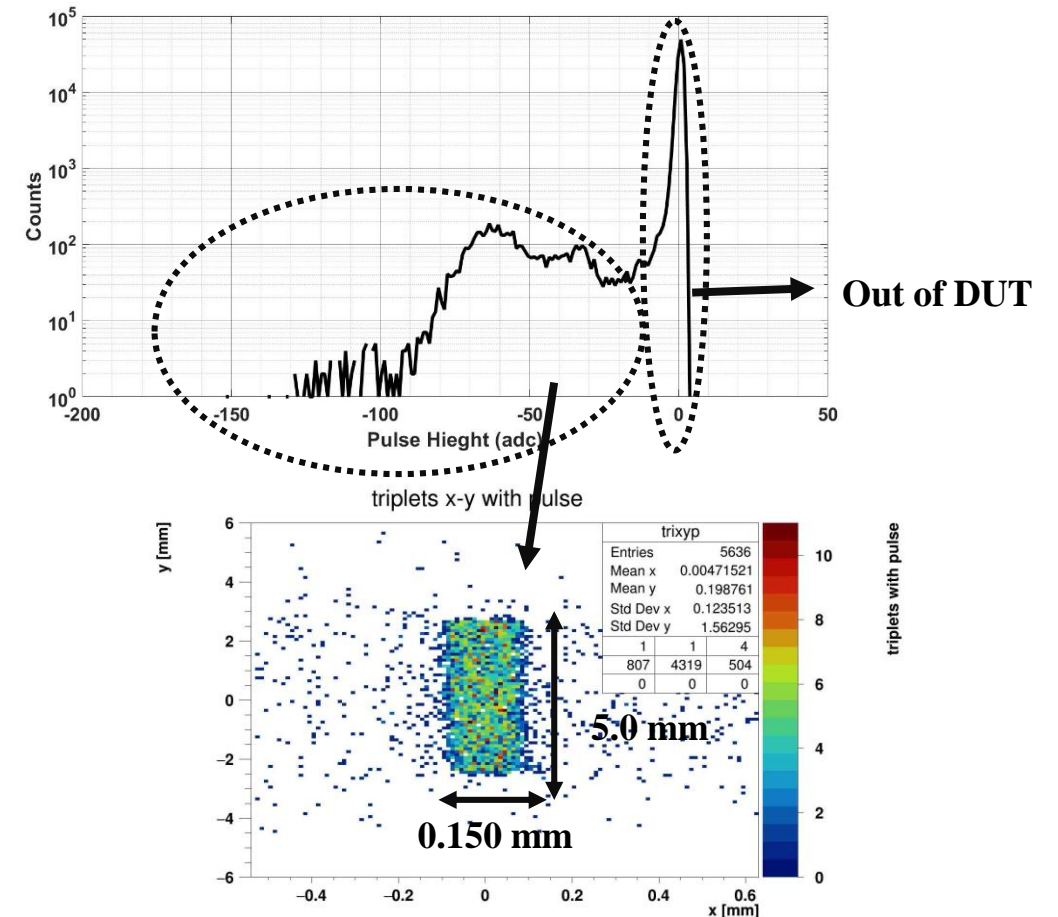
- Non-irradiated

Observations:

- Pulse height distribution of the DUT for all events
- Reconstructed tracks with amplitude over offline threshold

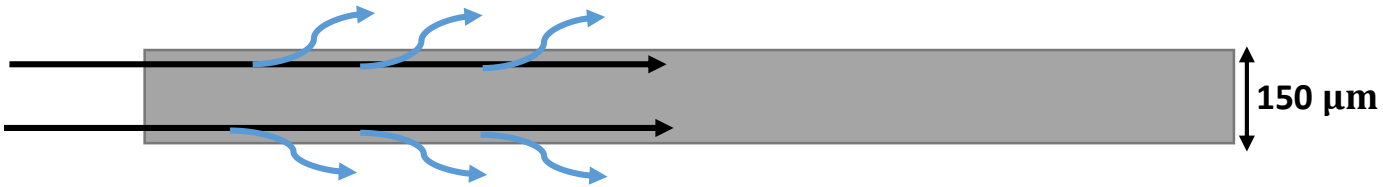
Conclusions:

- Most of tracks are out of the DUT plane
- 1~2 % of tracks produce pulse in the diode

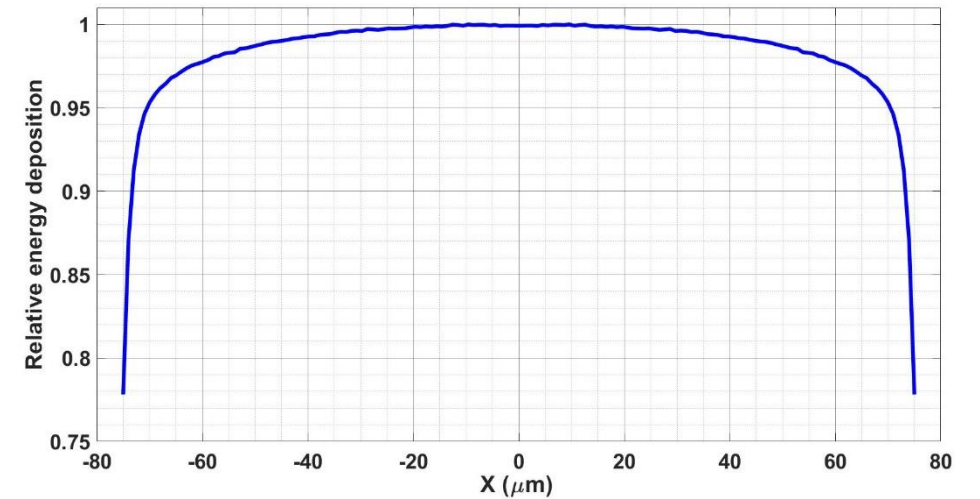


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Back up, GEANT4 simulation result



Less energy deposition at edges than center



Charge profile, non-irradiated diode

Measurement conditions:

- Temperature: -20 C
- $V_{\text{bias}} = 20, 100, 200, 300 \text{ V}$
- $\theta : 0^\circ$

DUT:

- Non-irradiated

Observations:

- At bias voltage of 20 V, the diode is only partially depleted from the front side. No charge collection in the rear side.
- For bias voltages above 100 V, the charge profile remains unchanged.

